#### § 98.86

Therefore, whenever a quality-assured value of a required parameter is unavailable, a substitute data value for the missing parameter shall be used in the calculations. The owner or operator must document and keep records of the procedures used for all such estimates.

- (a) If the CEMS approach is used to determine combined process and combustion  $CO_2$  emissions, the missing data procedures in §98.35 apply.
- (b) For CO<sub>2</sub> process emissions from cement manufacturing facilities calculated according to §98.83(d), if data on the carbonate content (of clinker or CKD), noncalcined content (of clinker or CKD) or the annual organic carbon content of raw materials are missing, facilities must undertake a new analysis.
- (c) For each missing value of monthly clinker production the substitute data value must be the best available estimate of the monthly clinker production based on information used for accounting purposes, or use the maximum tons per day capacity of the system and the number of days per month.
- (d) For each missing value of monthly raw material consumption the substitute data value must be the best available estimate of the monthly raw material consumption based on information used for accounting purposes (such as purchase records), or use the maximum tons per day raw material throughput of the kiln and the number of days per month.

#### § 98.86 Data reporting requirements.

In addition to the information required by §98.3(c), each annual report must contain the information specified in paragraphs (a) and (b) of this section, as appropriate.

- (a) If a CEMS is used to measure CO<sub>2</sub> emissions, then you must report under this subpart the relevant information required by §98.36(e)(2)(vi) and the information listed in this paragraph(a):
- (1) Monthly clinker production from each kiln at the facility.
- (2) Monthly cement production from each kiln at the facility.
- (3) Number of kilns and number of operating kilns.
- (b) If a CEMS is not used to measure  $CO_2$  emissions, then you must report

the information listed in this paragraph (b) for each kiln:

- (1) Kiln identification number.
- (2) Monthly clinker production from each kiln.
- (3) Annual cement production at the facility.
- (4) Number of kilns and number of operating kilns.
- (5) Quarterly quantity of CKD not recycled to the kiln for each kiln at the facility.
- (6) Monthly fraction of total CaO, total MgO, non-calcined CaO and non-calcined MgO in clinker for each kiln (as wt-fractions).
- (7) Method used to determine non-calcined CaO and non-calcined MgO in clinker.
- (8) Quarterly fraction of total CaO, total MgO, non-calcined CaO and non-calcined MgO in CKD not recycled to the kiln for each kiln (as wt-fractions).
- (9) Method used to determine non-calcined CaO and non-calcined MgO in CKD.
- (10) Monthly kiln-specific clinker CO<sub>2</sub> emission factors for each kiln (metric tons CO<sub>2</sub>/metric ton clinker produced).
- (11) Quarterly kiln-specific CKD CO<sub>2</sub> emission factors for each kiln (metric tons CO<sub>2</sub>/metric ton CKD produced).
- (12) Annual organic carbon content of raw kiln feed or annual organic carbon content of each raw material (wt-fraction, dry basis).
- (13) Annual consumption of raw kiln feed or annual consumption of each raw material (dry basis).
- (14) Number of times missing data procedures were used to determine the following information:
- (i) Clinker production (number of months).
- (ii) Carbonate contents of clinker (number of months).
- (iii) Non-calcined content of clinker (number of months).
- (iv) CKD not recycled to kiln (number of quarters).
- (v) Non-calcined content of CKD (number of quarters)
- (vi) Organic carbon contents of raw materials (number of times).
- (vii) Raw material consumption (number of months).
- (15) Method used to determine the monthly clinker production from each

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kiln reported under (b)(2) of this section, including monthly kiln-specific clinker factors, if used.

[74 FR 56374, Oct. 30, 2009, as amended at 75 FR 66461, Oct. 28, 2010]

#### §98.87 Records that must be retained.

- (a) If a CEMS is used to measure  $CO_2$  emissions, then in addition to the records required by  $\S98.3(g)$ , you must retain under this subpart the records required for the Tier 4 Calculation Methodology in  $\S98.37$ .
- (b) If a CEMS is not used to measure  $CO_2$  emissions, then in addition to the records required by §98.3(g), you must retain the records specified in this paragraph (b) for each portland cement manufacturing facility.
- (1) Documentation of monthly calculated kiln-specific clinker CO<sub>2</sub> emission factor.
- (2) Documentation of quarterly calculated kiln-specific CKD  ${\rm CO_2}$  emission factor.
- (3) Measurements, records and calculations used to determine reported parameters.

 $[75 \; \mathrm{FR} \; 66461, \; \mathrm{Oct.} \; 28, \; 2010]$ 

### § 98.88 Definitions.

All terms used in this subpart have the same meaning given in the Clean Air Act and subpart A of this part.

## Subpart I—Electronics Manufacturina

Source: 75 FR 74818, Dec. 1, 2010, unless otherwise noted.

# §98.90 Definition of the source category.

- (a) The electronics manufacturing source category consists of any of the production processes listed in paragraphs (a)(1) through (a)(5) of this section that use fluorinated GHGs or  $N_2O$ . Facilities that may use these processes include, but are not limited to, facilities that manufacture micro-electromechanical systems (MEMS), liquid crystal displays (LCDs), photovoltaic cells (PV), and semiconductors (including light-emitting diodes (LEDs)).
- (1) Any electronics production process in which the etching process uses plasma-generated fluorine atoms and

other reactive fluorine-containing fragments, that chemically react with exposed thin-films (e.g., dielectric, metals) or substrate (e.g., silicon) to selectively remove portions of material.

- (2) Any electronics production process in which chambers used for depositing thin films are cleaned periodically using plasma-generated fluorine atoms and other reactive fluorine-containing fragments.
- (3) Any electronics production process in which wafers are cleaned using plasma generated fluorine atoms or other reactive fluorine-containing fragments to remove residual material from wafer surfaces, including the wafer edge.
- (4) Any electronics production process in which the chemical vapor deposition (CVD) process or other manufacturing processes use  $N_2O$ .
- (5) Any electronics manufacturing production process in which fluorinated heat transfer fluids are used to cool process equipment, to control temperature during device testing, to clean substrate surfaces and other parts, and for soldering (e.g., vapor phase reflow).

[75 FR 74818, Dec. 1, 2010, as amended at 77 FR 10380, Feb. 22, 2012]

#### § 98.91 Reporting threshold.

- (a) You must report GHG emissions under this subpart if electronics manufacturing production processes, as defined in §98.90, are performed at your facility and your facility meets the requirements of either §98.2(a)(1) or (a)(2). To calculate total annual GHG emissions for comparison to the 25,000 metric ton CO2e per year emission threshold in §98.2(a)(2), follow the requirements of §98.2(b), with one exception. Rather than using the calculation methodologies in §98.93 to calculate emissions from electronics manufacturing production processes, calculate emissions of each fluorinated GHG from electronics manufacturing production processes by using paragraphs (a)(1), (a)(2), or (a)(3) of this section, as appropriate, and then sum the emissions of each fluorinated GHG by using paragraph (a)(4) of this section.
- (1) If you manufacture semiconductors or MEMS you must calculate annual production process emissions of